

Notice of References Cited	Application/Control No. 10/549,683	Applicant(s)/Patent Under Reexamination SUDA ET AL.	
	Examiner MATTHEW J. SONG	Art Unit 1792	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Li et al, "Field-ion scanning tunneling microscopy study of the atomic structure of 6H-SiC (0001) surfaces cleaned by in situ Si molecular beam etching," J. Appl. Phys. 80 (4), 15 August 1996, pg 2524-2526.
	V	Kugimiya et al., "Si-Beam Radiation Cleaning in Molecular beam epitaxy," Japanese Journal of Applied Physics Vol 24, No. 5, May 1985, pp 564-567.
	W	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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